

## Exfoliated MoTe<sub>2</sub> Field-Effect Transistor

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Transition metal dichalcogenides (TMD) are materials with the form MX<sub>2</sub> where M is a metal and X can be Se, S, or Te. These materials have covalent bonding within the layers and Van der Waals bonding between the layers [1]. Unlike graphene, the existence of a band gap eliminates the need to form nanoribbons for two-dimensional crystal tunnel field-effect transistors (TFETs). Among TMDs, molybdenum ditelluride MoTe<sub>2</sub> has the lowest band gap (1 eV) which makes it highly suitable for TFET application. In this paper, we report the first fabrication and electrical characteristics of a MoTe<sub>2</sub> FET, made on exfoliated multilayer crystals.

The MoTe<sub>2</sub> process flow for forming back-gated FETs begins with the formation of a 30 nm atomic-layer-deposited Al<sub>2</sub>O<sub>3</sub> back-gate dielectric on a *p*+ Si substrate. The multilayer MoTe<sub>2</sub> crystals were mechanically exfoliated from bulk MoTe<sub>2</sub> (from American Elements Company with 99.9% purity) and transferred onto the Al<sub>2</sub>O<sub>3</sub> using scotch tape. Electron beam deposited Ti followed by Au was used to form source, drain and back gate metallization.

Energy dispersive X-ray analysis (EDX) shows that the exfoliated MoTe<sub>x</sub> (*x*=1.88) flakes mainly consist of Mo and Te (C, O, and Cu are observed, but they are from the mounting grid). Transmission electron micrographs of the MoTe<sub>2</sub> flakes have been examined. Both high-resolution images and electron diffraction patterns confirm the crystal structure with a lattice parameter of 0.35 nm, the same as the bulk lattice parameter. Other lattice parameters are as follows: *b*=3.53Å, *c*=13.88Å,  $\alpha=\beta=90^\circ$ ,  $\gamma=120^\circ$  and space group P63/mmc (#194).

The transfer characteristic, i.e. drain current vs. back gate voltage,  $I_D-V_{BG}$  shows that conductance is achieved at positive gate voltages consistent with *n*-type channel conduction. Although at different back gate voltages both on and off currents are different, here, we define the on/off current ratio to be the maximum achievable on to off current ratio. The on/off current ratio increases as temperature decreases from 1.98 at room temperature to 320.95 at 4K. At room temperature the off current is high, 4.75  $\mu$ A, presumably due to residual positive charge at the Al<sub>2</sub>O<sub>3</sub>/MoTe<sub>2</sub> interface. At 300K the current is not saturated and the delayed turn-on shows evidence of a Schottky contact behavior.

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[1] S. Kim, A. Konar, W. S. Hwang, J. Hak Lee, J. Lee, J. Yang, C. Jung, H. Kim, J. B. Yoo, J.Y. Choi, Y. W. Jin, S. Y. Lee, D. Jena, W. Choi, K. Kim, "High-mobility and low-power thin-film transistors based on multilayer MoS<sub>2</sub> crystals," *Nature Communications* 3, 1011, (Aug 2012).

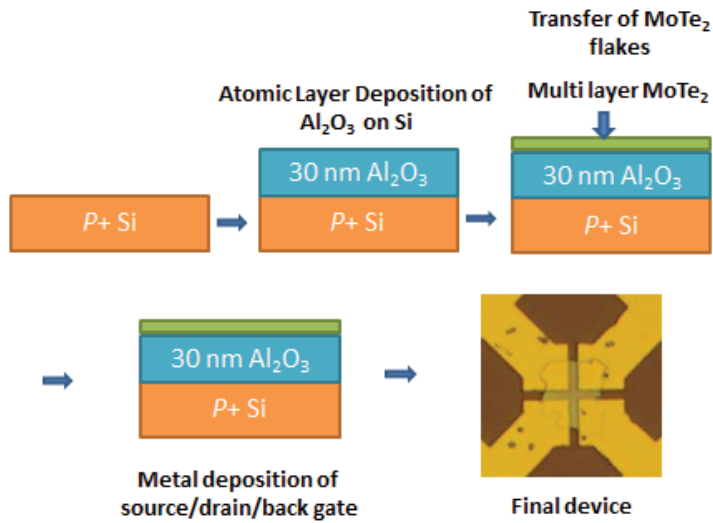


Figure 1: Fabrication process of MoTe<sub>2</sub> transistor

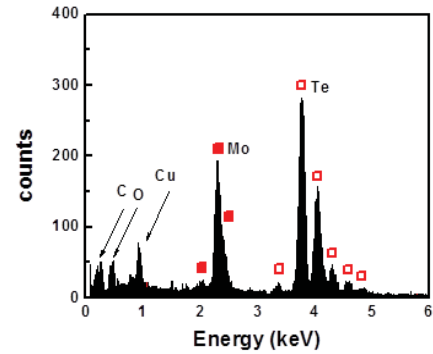


Figure 2: Energy dispersive X-ray analysis (EDX)

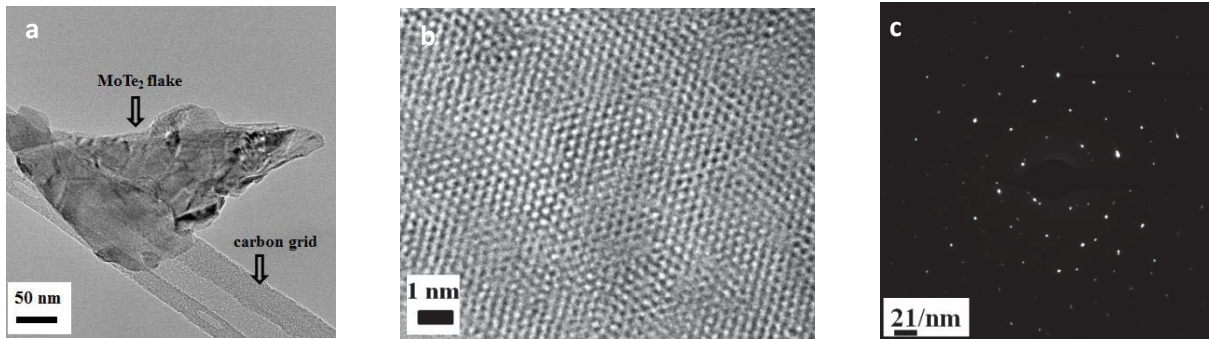


Figure 3: (a) Transmission electron micrograph (TEM) of a MoTe<sub>2</sub> flake, (b) high-resolution TEM, and (c) electron diffraction pattern

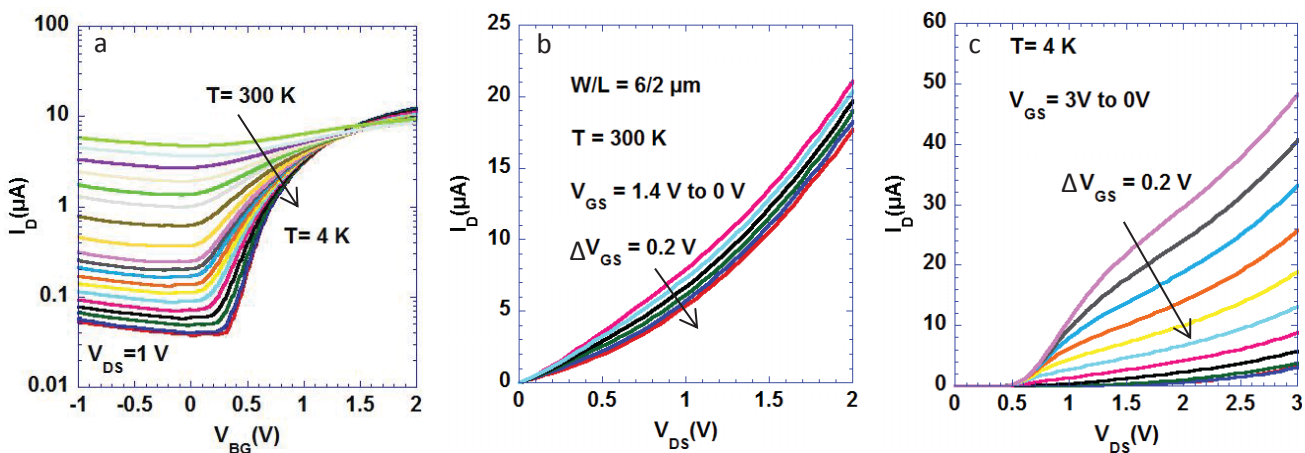


Figure 4: MoTe<sub>2</sub> transistor characteristics for  $W/L=6/2 \mu\text{m}$ . (a) Temperature dependence of the transfer characteristic,  $I_D$ - $V_{BG}$  characteristics, and the common-source transistor characteristics at (b) 300 K, and at (c) 4 K.